

Supplementary Materials: Research on the Thickness and Microstructure of Plate-like TiO₂ by the Nanosheet-Seeding Growth Technique

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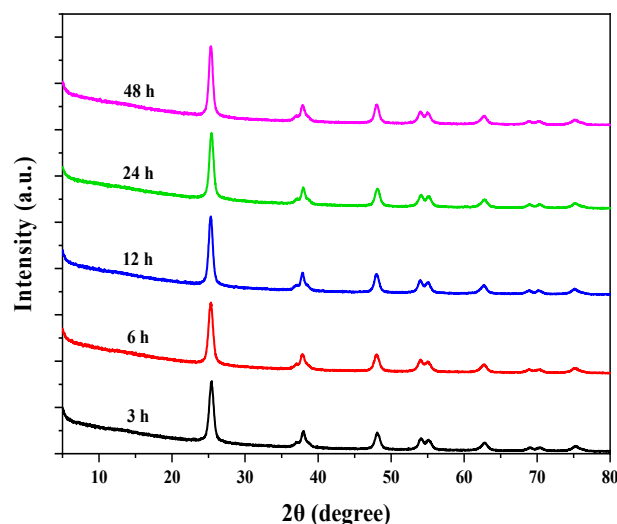


Figure S1. XRD of the samples with different synthesis time, 3 h, 6 h, 12 h, 24 h and 48h.

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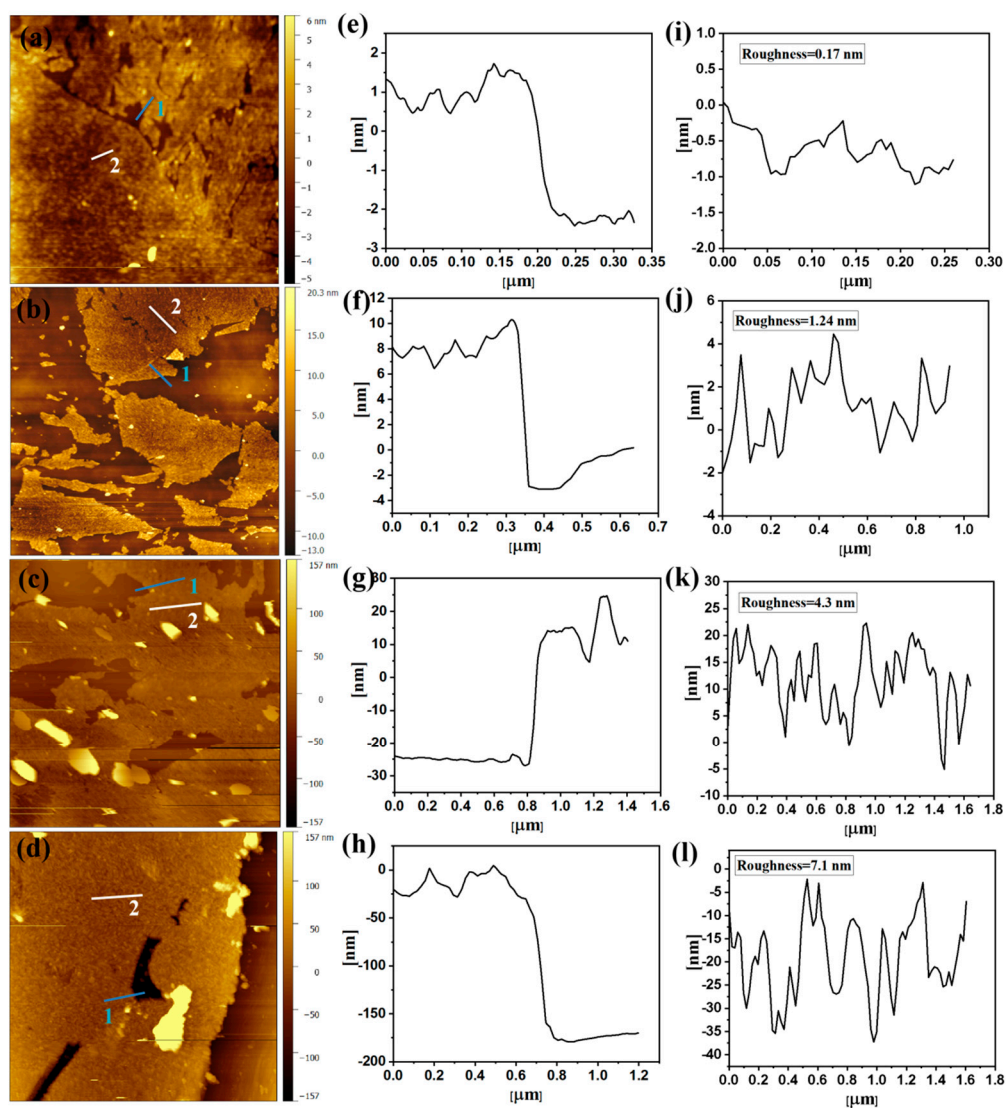


Figure S2. AFM images of TiO₂ growth on monolayer T_{0.87}O₂ nanosheet thin film, (a) 2 h, (b) 4 h, (c) 8 h and (d) 16 h.

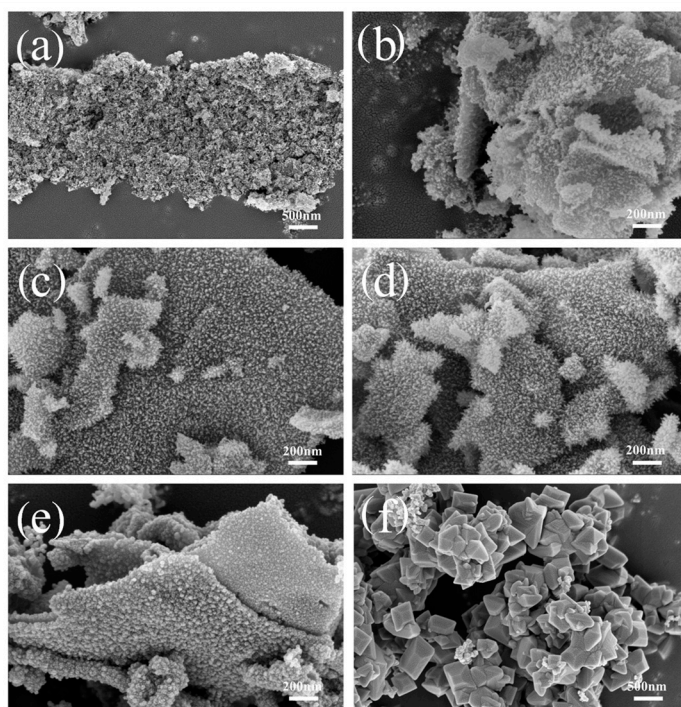


Figure S3. Typical SEM images of the samples, (a) 0.025 M, (b) 0.05 M, (c) 0.1 M, (d) 0.15 M and (e) 0.2 M; (f) SEM image of the sample at 0.3 M after calcination.

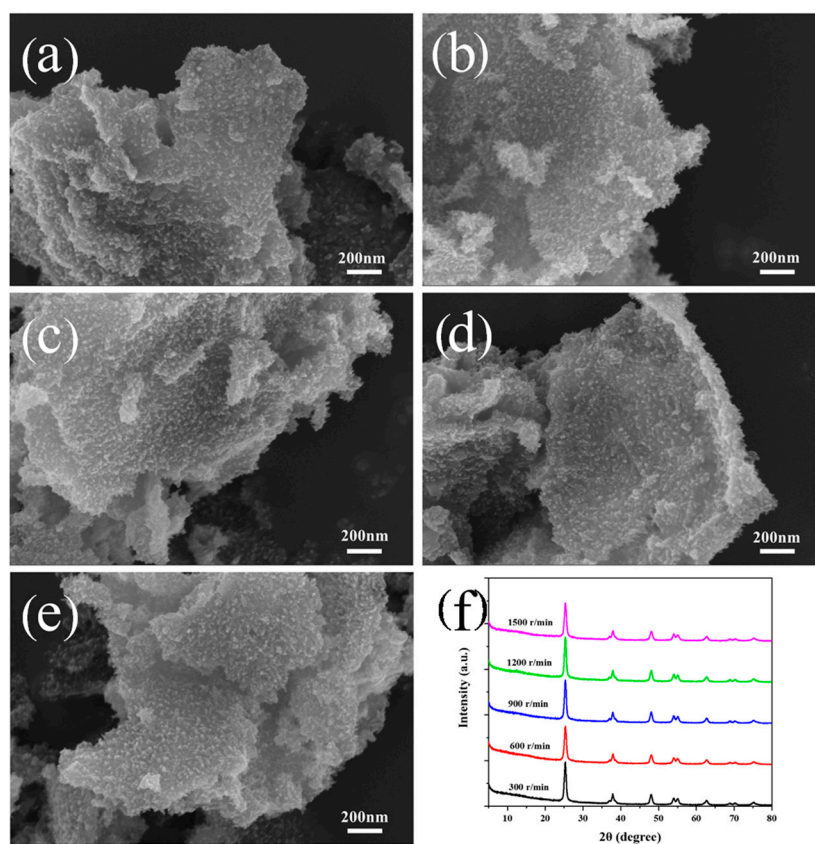


Figure S4. SEM images of the samples with different stirring rates, (a) 300 rpm, (b) 600 rpm, (c) 900 rpm, (d) 1200 rpm and (e) 1500 rpm; (f) XRD patterns of the samples.

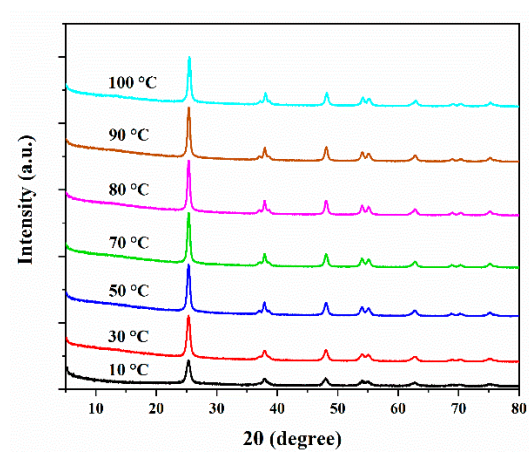


Figure S5. XRD of the samples with different synthesis temperatures, 10 °C, 30 °C, 50 °C, 70 °C, 80 °C, 90 °C and 100 °C.